Special Issue

Accelerometer and Magnetometer: From Fundamentals to Applications, 2nd Edition

Message from the Guest Editors

Accelerometers and magnetometers are widely applied in consumer electronics, automobiles, precision manufacturing and defense, aerospace and geophysical functions. MEMS technology can meet these applications' requirements of Cost, Size, Weight and Power (CSWaP) and performance, although some sensors still demonstrate scientific barriers to such uses. Key challenges include, but are not limited to, the following: microfabrication processes, new materials, device design and optimization, interface circuits, signal processing and sensor fusions. In addition, the promising new mechanisms of micromachines, such as atomic, optical levitation and optomechanical technologies, are of great interest. This Special Issue calls for original research papers and reviews detailing state-of-the-art results on the present topic.

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